

IN THE SPECIFICATION

Please amend the Specification as follows:

[0011] As illustrated in FIG. 2 generally, an IL template, according to the invention, comprises an array of moveable, individually addressable, and spaced-apart rods or plungers (FIG. 2a). The template or mask can be configured to provide a particular pattern by programming the array of plungers such that certain of the plungers are in an "up" or actuated configuration (FIG. 2b). The pattern of the "up" plungers can then be impressed onto a polymer film by conventional IL methods such as described above. Conversely, an impossibly pattern can also be configured by moving certain of the plungers into a "down" position; the remaining "up" plungers then form the desired pattern. This mode of patterning the template is illustrated in FIG. 2, wherein certain plungers have been moved into the "down" position to produce an "L" when stamped into a deformable material such as a photoresist. Individual plungers can be displaced by actuation methods known to the microelectromechanical (MEMS) art. These include, but are not limited to: thermal, electrostatic, pressure (by bubble formation), microfluidic, or magnetic actuation methods.

[0023] As a second step in making a plunger configuration, a capping wafer is prepared. Referring now to FIG. 4, a capping wafer 410 is coated on both the upper and lower surfaces with a photoresist material 415. The photoresist covering lower surface is patterned (FIG. 4a) followed by a shallow pattern transfer (etch) (FIG. 4b). A second mask is deposited on the [[on]] lower surface and a deep pattern etch transfer etch is done to form a stepped structure such as that illustrated in FIG. 4c. Finally, the second mask is stripped from the lower surface as well as the photoresist layer covering the upper surface.

[0029] Other means of actuating the array of plungers to produce a desired configuration will be obvious to those skilled in the microelectromechanical (MEMS) art. These include, but are not limited to thermal, pressure (by bubble formation), microfluidic, or magnetic actuation methods.